

PATENT ABSTRACTS OF JAPAN

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(57)Abstract:

PURPOSE: To surely execute the conduction of the tip of a contact probe and a substrate and to improve the reliability of an inspection by forming the tip of a plunger to a hemispherical shape or a conical shape.

CONSTITUTION: A plunger 1 can move in the longitudinal direction in a housing 2. In this regard, the tip shape of the plunger 1 is formed to a hemispherical shape or a conical shape, and also, on the surface of this hemispherical shape, many projections 3 are formed. As a result, when a contact of the side of a substrate to be inspected comes into contact, while sliding on the surface of the tip of the plunger 1, the projections 3 are brought to self-polishing. Accordingly, a conducting property of the tip can be secured extending over a long period of time.

